

Surface Modification of PDMS Substrates

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Introduction

- **Advantage of PDMS**

PDMS為一疏水性高分子材料，已被廣泛用於微鑄模製程（micro-molding process）及微流體通道（microfluidic channel）材質。其優點為具可塑性高且可高溫滅菌，透光性佳，且具良好生物相容性。

- 本研究針對PDMS作表面處理，並且經過氧電漿以及化學處理的方式，使其局部永久性地定義為親水區。將其應用於微閥開關的控制上，可對樣品流作多工的取樣以及反應，更可以將之整合於其他微流體系統。

Surface Modification of PDMS

- **Methods**
 - Oxygen plasma treatment
 - Chemical treatment
 - Stored in pure water
 - Stores in vacuum
- **Purpose**
 - Produce hydrophilic group, ex. -OH、-COOH

Prescription of PDMS Chemical Treatment

AMPS (2-Acrylamido-2-methyl-1-propanesulfonic acid, 99%)	10mg
D.I.water	1ml
1N HNO ₃	3~5d
Ammonium cerium(V) nitrate	5mg

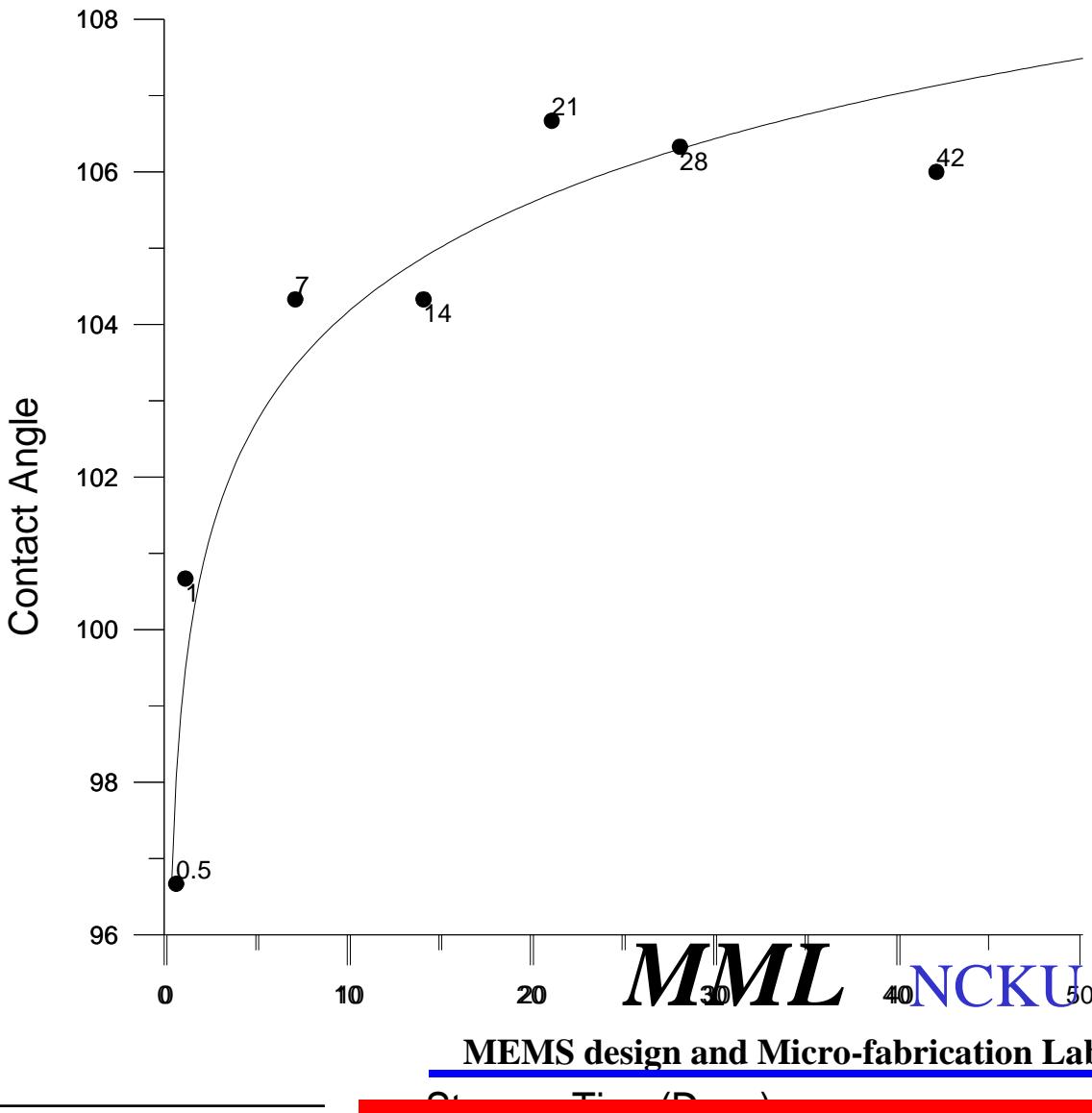
Methods of PDMS surface treatment

	Oxygen Plasma	Chemical Treatment	Stored in DI water
A(Native PDMS)	X	X	X
B	V	X	X
C	V	X	V
D	V	V	X
E	V	V	V

	Oxygen Plasma	Chemical Treatment	Stored in vacuum
F	V	V	V

• Type B

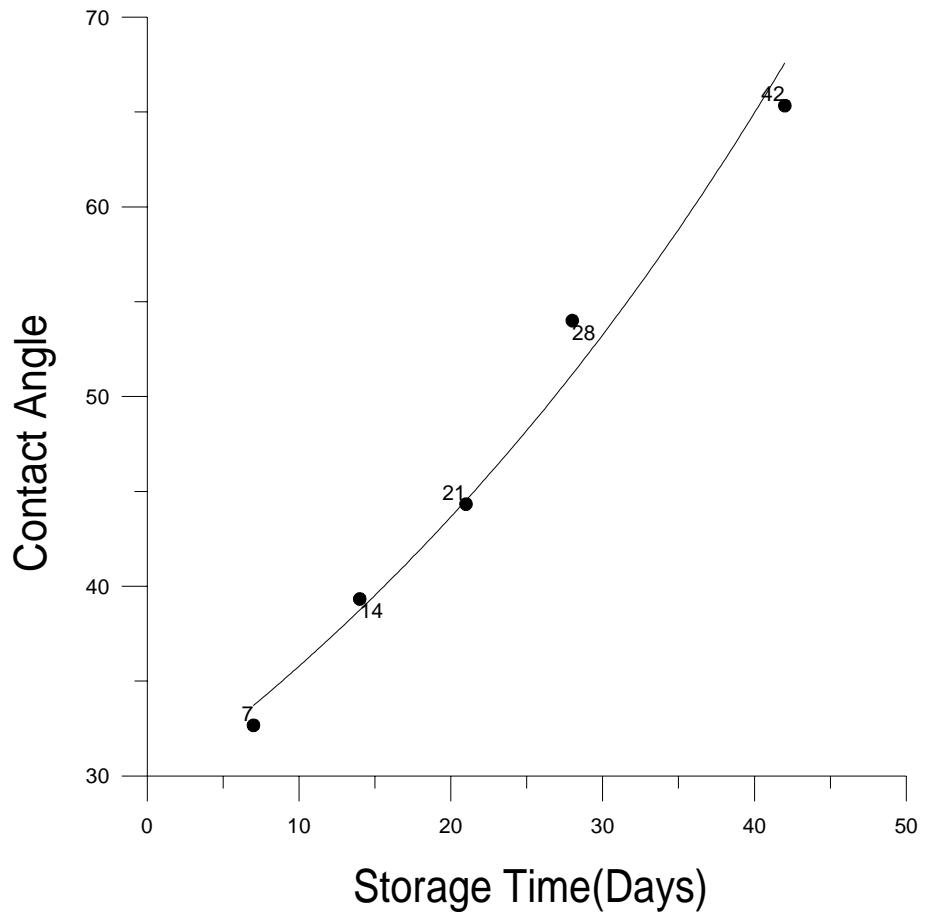
	Oxygen Plasma	Chemical Treatment	Stored in DI water
B	V	X	X



- Type D

	Oxygen Plasma	Chemical Treatment	Stored in DI water
D	V	V	X

Days	Contact Angle
0.5	<10
1	<10
7	32.67
14	39.33
21	44.33
28	54.00
42	65.33



	Oxygen Plasma	Chemical Treatment	Stored in DI water
A(Native PDMS)	X	X	X

The contact angle of Type A = 112°

	Oxygen Plasma	Chemical Treatment	Stored in DI water
C	V	X	V
E	V	V	V

The contact Angle of type C and E $< 10^\circ$

	Oxygen Plasma	Chemical Treatment	Stored in vacuum
F	V	V	V

時間(day)	contact angle
1	$< 10^\circ$
3	$< 10^\circ$
5	$< 10^\circ$
7	$< 10^\circ$
14	$< 10^\circ$
21	$< 10^\circ$
28	$< 10^\circ$
35	$< 10^\circ$
42	$< 10^\circ$

The contact Angle of type F $< 10^\circ$

Conclusions

- 經過氧電漿和化學處理後的晶片，其表面性質並不會隨著時間而改變，穩定性佳。
- 本研究成功地利用PDMS表面性質的處理，應用於新式微閥開關的控制
- 微閥開關晶片結構單一，所以可以準確地控制樣品流的動作和反應。更進一步地可以將之與其他微流體元件整合，例如微幫浦（micro pump），規劃成一完整多工樣品取樣反應系統。